

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

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In re Patent Application of:  
Masashi Kawasaki et al.

Application No.: 10/588,283

Confirmation No.: 5019

Filed: July 23, 2007

Art Unit: 1794

For: METHOD OF MANUFACTURING THIN  
FILM, METHOD OF MANUFACTURING p-  
TYPE ZINC OXIDE THIN FILM AND  
SEMICONDUCTOR DEVICE

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Examiner: J. C. Langman

**RESPONSE TO RESTRICTION REQUIREMENT**

MS Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Madam:

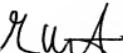
In response to the restriction requirement set forth in the Office Action mailed March 30, 2009, Applicant hereby elects Group 1, claims 1-9, and 21, drawn to a method, for continued examination with traverse.

If the search and examination of all the claims in an application can be made without serious burden, the examiner must examine them on the merits, even though they include claims to independent or distinct inventions. *MPEP 803*. The Office Action has failed to show that it would be a serious burden on the Examiner to examine all claims. Therefore, the election requirement is improper and should be withdrawn.

Applicants respectfully request that the restriction be withdrawn and all claims examined.

Dated: April 30, 2009

Respectfully submitted,

By  #41,198  
Thomas J. D'Amico

Registration No.: 28,371  
David T. Beck  
Registration No.: 54,985  
DICKSTEIN SHAPIRO LLP  
1825 Eye Street, NW  
Washington, DC 20006-5403  
(202) 420-2200  
Attorneys for Applicant